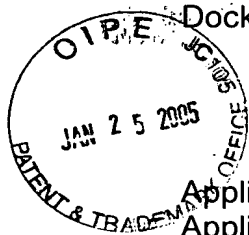


Docket No.: L&L-I0242



IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

Applic. No. : 10/694,593  
Applicant : Olaf Storbeck, et al.  
Filed : October 27, 2003  
Art Unit : 2811  
Title : Method for Minimizing the Vapor Deposition of Tungsten-Oxide  
During the Selective Side Wall Oxidation of Tungsten-Silicon  
Gates  
Docket No. : L&L-I0242  
Customer No. : 24131

STATUS LETTER

Commissioner for Patents,  
P.O. Box 1450, Alexandria, VA 22313-1450

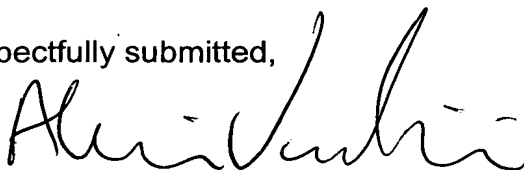
Sir:

It is respectfully requested that this Status Letter be returned to:

LERNER AND GREENBERG, P.A.  
Post Office Box 2480  
Hollywood, FL 33022-2480  
Tel: (954) 925-1100  
Fax: (954) 925-1101

with an indication as to when an action may be expected.

Respectfully submitted,

  
Alexia J. Vrahimis

Date: January 21, 2005

/av